

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Yunlong LI et al.

Group Art Unit: 1763

Application No.: 09/123,352

Examiner: R. Zervigon

Filed: July 28, 1998

Docket No.: 100869

For: PLASMA GENERATION APPARATUS

AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action mailed October 27, 1999 and further to the April 13, 2000 personal interview, please amend the above-identified application as follows:

IN THE CLAIMS:

Please amend claims 1, 3, 7, 8, 10-14 and 16 as follows:

1. (Twice Amended) A plasma generation apparatus comprising:
- a vacuum vessel having a plasma generation region established in the interior thereof;
- a gas [induction means for inducting] inductor that inducts discharge gas into said interior of said vacuum vessel;
- an exhaust [means for exhausting] that exhausts the atmosphere in the [in the] interior of said vacuum vessel;
- a [cylindrical] tube-shaped discharge electrode fashioned so as to enclose said plasma generation region;
- a first high-frequency electric power [application means for applying] applicator that applies high-frequency electric power to said discharge electrode;